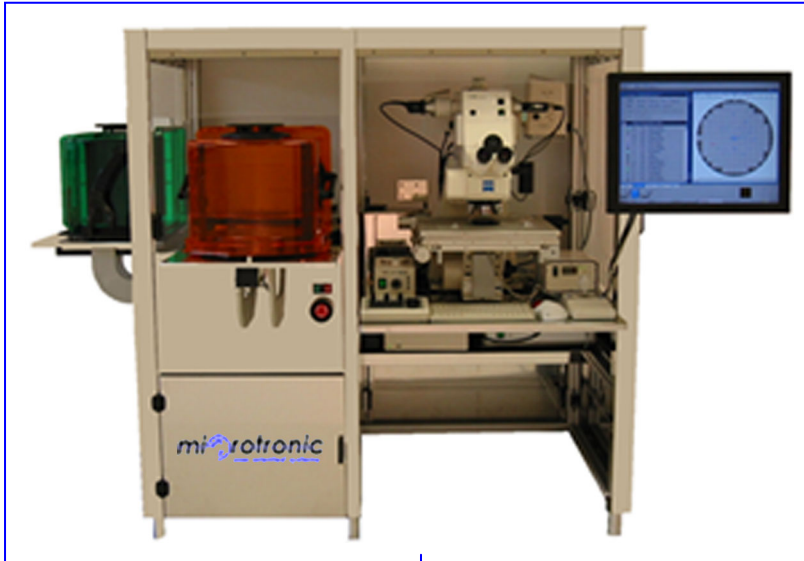


The **300FA** Automated Failure Analysis system integrates more applications with ergonomic ease of operation. A small footprint, high speed, low cost per feature and serviceability contribute to its' award winning CoO*.



SITEview™ software
Applications Include:

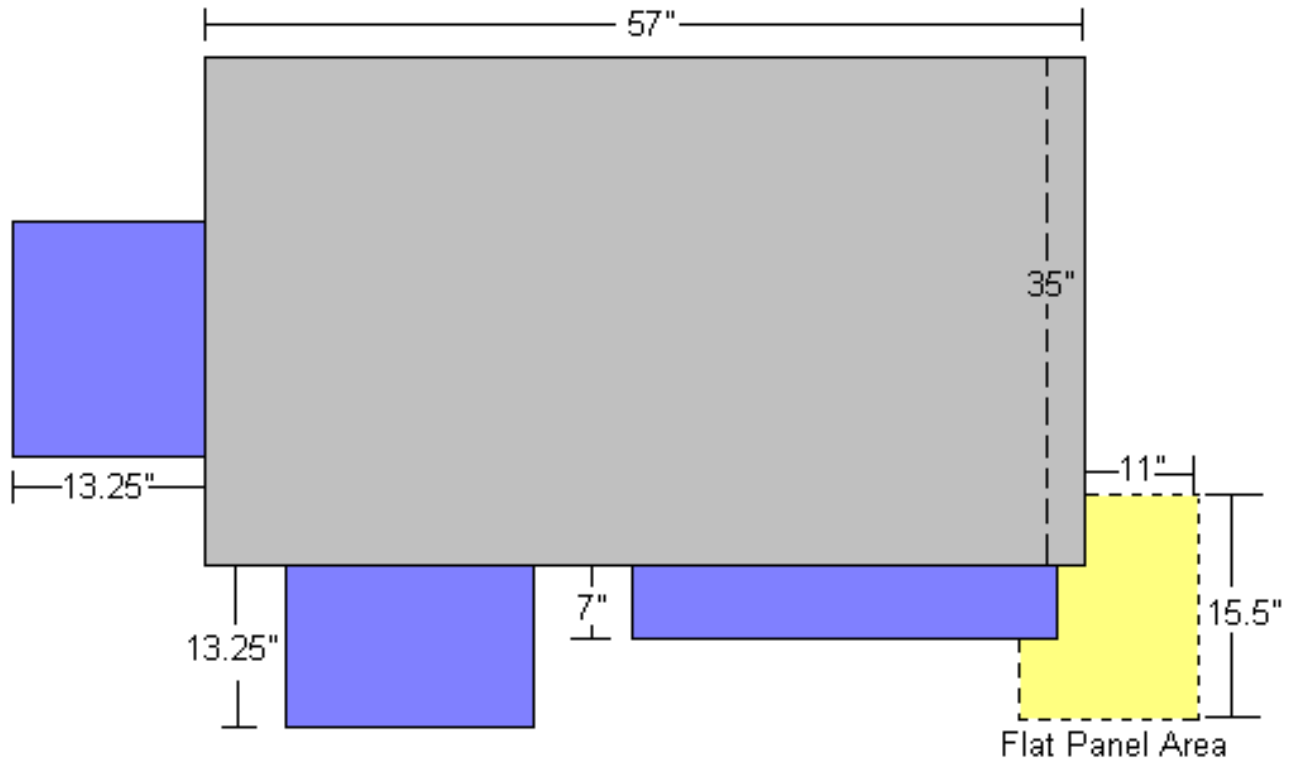
- ▶ FA Navigation Software
- ▶ User customizable screen
- ▶ Automated “manual load” mode for single wafer or wafer piece loading with Deskew
- ▶ Defect Review – visit defect sites using defect review file data (any file format)
- ▶ Sorting
- ▶ Second Optical Inspection
- ▶ Image Storage & Retrieval
- ▶ GEM/SECS II
- ▶ Host Communication – LAN
- ▶ UV Microscope Interface

Custom Configurations:

- ▶ One Bridge Tool for both 200 & 300mm Wafers. Auto wafer size recognition, no calibration
- ▶ 1 or 2 Cassette Platforms for manual loading in FA lab
- ▶ FOUP indexers available
- ▶ OCR – Dual wafer ID recognition
Alpha-numeric for 200mm & 2D Matrix for 300mm
- ▶ **Photonic™** Laser Marker compatible
- ▶ Zeiss Optics - BF, DF, DIC, VIS & UV Confocal modes with 80 - 100nm visibility (shown)
- ▶ Can integrate all major microscope brands including your existing scopes
- ▶ Hi – Precision Stage with embedded 12” x12” Reticle for maximum accuracy
- ▶ 20” Hi Res Flat Panel Display
- ▶ Active Mini Environment or Passive Enclosure (shown) or open table top design



*Lucent - Vendor of the Year Award
lowest CoO worldwide - Last 2 yrs. held



- ▶ Small footprint
- ▶ Mounted on casters and extendable leveling posts for mobility
- ▶ 120V/20A Single Phase, One power cord
- ▶ Vacuum – 25"/600mm Hg
- ▶ No process air or N2
- ▶ Configurable for Fab or FA lab
- ▶ User customizable enclosure & layout
- ▶ Field serviceable robot & peripherals

Our commitment to you:
"...We combine the highest quality components with customizable integration to provide true user oriented systems. Tell us your needs, hardware or software, we'll build to your specs..."
Reiner Fenske - President